

**PATENT APPLICATION**  
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q82315

Michel PUECH, et al.

Appln. No.: 10/500,654

Group Art Unit: 1765

Confirmation No.: 2879

Examiner: Mahmoud DAHIMENE

Filed: July 2, 2004

For: A METHOD AND APPARATUS FOR ANISOTROPICALLY ETCHING SILICON  
WITH A HIGH ASPECT RATIO

**PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

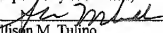
Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of  
three months, extending the time for responding to the Office Action of June 15, 2006 to  
December 15, 2006.

Please charge the statutory fee of \$1020.00 to Deposit Account No.: 19-4880. The  
USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the  
Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said  
Deposit Account. A duplicate copy of this sheet is enclosed.

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WASHINGTON OFFICE  
**23373**  
CUSTOMER NUMBER

Respectfully submitted,

  
Allison M. Tulinio  
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Date: December 12, 2006